SHORT COURSE ON

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Circle Reader Response # 19

He who borrows lenses borrows trouble

Sterling Newberry

This adage for my students was obviously inspired by "He who steals my is easily accomplished, while the incompatibility of the optical components is which have their corrections self contained within the lens.

not usually apparent. This incompatibility can range from easily recognized blurring of the image to only slight loss of resolution which leads to inferior work or much wasted time before the problem is recognized.

I bring this reminder up because many who work primarily with electron microscopes have either forgotten this warning or were never exposed to formal training for the optical microscope even though their work requires use of optical purse steals trash" but the lens borrower may be in for more serious trouble microscopes. One should know or recall that the designer of your lenses may put than the purse snatcher. This comes about because the eyepiece fit and the all the aberration corrective elements into the objective lens alone or he may objective threads are standardized to a couple of standards so that the choose to put part of it into the eye piece or even an intermediate element. When mechanical interchange of components between different optical microscopes this is done, the resulting eye pieces and objectives cannot be mixed with lenses

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